

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified) JAN 02 2004				Docket No.		Serial No.		
LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT				AMAT/8284/CMP/W-C/RKK		10/676,182		
(Use several sheets if necessary)				Applicant Verhaverbeke		Confirmation No.: Unknown		
		Examiner Unknown		Filing Date September 30, 2003		Group Unknown		
U.S. Patent Documents								
*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
<i>Ja</i>	A1	5,326,490	07/05/94	Mori, et al.	252	79.2	11/15/91	
	A2	5,294,570	03/15/94	Fleming, Jr., et al.	437	239	01/29/92	
	A3	5,052,421	10/01/91	McMillen	134	2	07/27/90	
<i>Ja</i>	A4	4,220,706	09/02/80	Spak	430	318	05/10/78	
	A5							
	A6							
	A7							
	A8							
	A9							
Foreign Patent Documents								
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
<i>Ja</i>	B1	02/10480	02/07/02	WO	C23G	1/00	<input type="checkbox"/>	<input type="checkbox"/>
	B2	01/24244	04/05/01	WO	H01L	21/311	<input type="checkbox"/>	<input type="checkbox"/>
	B3	0 918 081 A1	05/26/99	EP	C09K	13/08	<input type="checkbox"/>	<input type="checkbox"/>
	B4	0 477 504 A1	04/01/92	EP	H01L	21/306	<input type="checkbox"/>	<input type="checkbox"/>
<i>Ja</i>	B5	7183287	07/21/95	JP	H01L	21/308	<input type="checkbox"/>	<input type="checkbox"/>
OTHER ART								
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.						
<i>Ja</i>	C1	Archer, et al. "Real Fab Comparisons Reveal Advantage to Inorganic-based Polymer Removal," Solid State Technology - Semiconductor Manufacturing and Wafer Fabrication, December 2002						
	C2	Archer, et al. "Removing Postash Polymer Residue from BEOL Structures Using Inorganic Chemicals," Micro, June 2001						
	C3	Verhaverbeke, et al., Improved Rinsing Efficiency After SPM (H_2SO_4/H_2O_2) by Adding HF, Proceedings of the Second International Symposium on Ultra-Clean Processing of Silicon Surfaces (1994)						
<i>Ja</i>	C4	Khan, "Use of Lithographically Defined Metal Masks in Selective Chemical Etching of Patterns in Thin Films: Microelectronic Applications," Thin Solid Films, 206 (1991) 269-274						
Examiner <i>S. Claudia</i>		Date Considered <i>7/20/05</i>						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								

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PTO/SB/08a (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

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**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT BY
APPLICANT**

(Use as many sheets as necessary)

Sheet

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of

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Application Number	10/676,182
Filing Date	September 30, 2003
First Named Inventor	Verhaverbeke
Group Art Unit	1746
Examiner Name	Unknown
Attorney Docket Number	AMAT/8284/CMP/W-C/RKK

Submission Date

September 23, 2004

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (³ known)			
JA	A1	US-6605230 B1	08/12/2003	Liaw, et al.	
JA	A2	US-6273959 B1	08/14/2001	Onishi, et al.	
	A3				
	A4				
	A5				
	A6				
	A7				
	A8				
	A9				
	A10				
	A11				
	A12				
	A13				
	A14				
	A15				
	A16				
	A17				
	A18				

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
DA	C1	International Search Report for PCT/US2004/003856 (AMAT/8284-PCT) dated July 28, 2004	
SA	C2	Written Opinion of the International Searching Authority for PCT/US2004/003856 (AMAT/8284-PCT) dated July 28, 2004	

Examiner

Schandley

Date Considered

7/20/05

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**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT & BY COUNSEL**

APPLICANT

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OCT 31 2004
U.S. PATENT & TRADEMARK OFFICE

Sheet

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First Named Inventor	Verhaverbeke
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Submission Date

September 28, 2004

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
XJ	A1	US-6630074 B1	10/07/2003	Rath, et al.	
	A2	US-5780363	07/14/1998	Delehanty, et al.	
	A3	US-4100014	07/11/1978	Kuhn-Kuhnenfeld, et al.	
XJ	A4	US- 200300209514 A1	11/13/2003	Ramachandran, et al.	
	A5				
	A6				
	A7				
	A8				
	A9				
	A10				
	A11				
	A12				
	A13				
	A14				
	A15				

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ³
		Country Code ² -Number ⁴ -Kind Code ⁵ (if known)				
XJ	B1	TW 0296405	01/21/1997	Jaw, et al.		
	B2	JP 58030135	02/22/1983	Shiyuichi		
	B3	JP 52033847	03/15/1977	Masaaki, et al.		
XJ	B4	UK 989,025	04/14/1965			

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
XJ	C1	Kelly, J.J., et al., "Electrochemical Aspects of the Beveling of Sputtered Permalloy Films," J. Electrochem Soc.: Electrochemical Science and Technology Vol. 125, No. 6 (June 1978) pp. 860-865	

Examiner

J. chaudhary

Date Considered

7/20/05

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